## Rajshahi University of Engineering and Technology



## RUET

## **Depart**ment of Electrical & Electronic Engineering

Course no. EEE 4166

Course title: Processing & Fabrication Technology Sessional

Experiment no. 5

**Experiment name:** Characterization of ZnO thin lim from XRD analysis and UV/Vis spectrophotometer

**Date of experiment:** July 26, 2023

**Date of submission:** August 1, 2023

Submitted to:	Submitted by:				
Dr. Md. Faruk Hossain	Ashraf Al- Khalique				
Professor	Roll: 1801171				
Dept. of Electrical & Electronic Engineering,	Session: 2018-2019				
Rajshahi University of Engineering and	Dept. of Electrical & Electronic Engineering,				
Technology.	Rajshahi University of Engineering and				
	Technology.				

Data table 5.1: XRD data for film thickness calculation

Sl. No.	2*Theta	Intensity	Sl. No.	2*Theta	Intensity
1	20	20	101	21.98	14
2	20.02	18	102	22	14
3	20.04	18	103	22.02	22
4	20.06	20	104	22.04	14
5	20.08	12	105	22.06	14
•••••	••••••	••••••	••••••	••••••	••••••
••••••	••••••	••••••	••••••	••••••	•••••
99	21.94	12	3499	89.98	18
100	21.96	12	3500	90	18

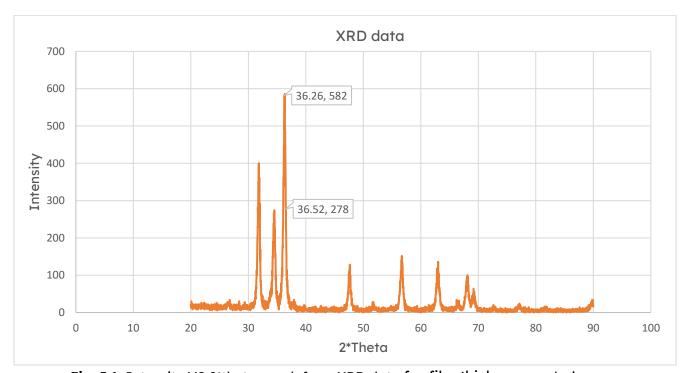


Fig. 5.1: Intensity VS 2\*theta graph from XRD data for film thickness analysis

## Data table 5.2: UV/Vis data for band gap calculation

wave	%Trans.	Trans.	log term	alpha	hv	(αhv)^.5	(αhv)^2
900	54.51	0.5451	2.263524	5212895	1.377778	2679.964809	13633787.91
899	54.474	0.54474	2.263811	5213556	1.37931	2681.62486	13681068.99
898	52.986	0.52986	2.275839	5241257	1.380846	2690.236112	13799758.72
•••••	••••••		*******	******	******	******	••••••
•••••	••••••		*******	******	******	******	••••••
894	54.391	0.54391	2.264473	5215081	1.387025	2689.506644	13915972.94
893	54.342	0.54342	2.264864	5215983	1.388578	2691.244672	13965189.03

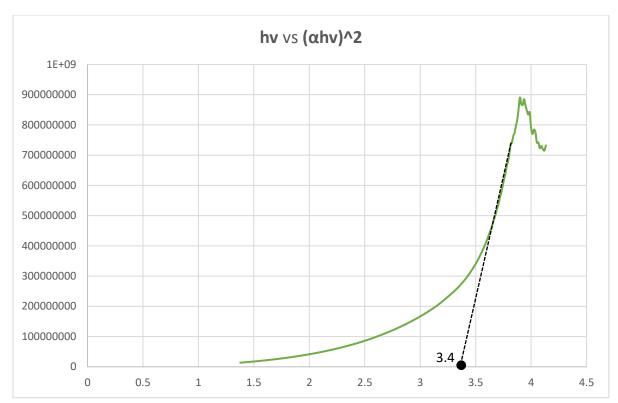


Fig. 5.2: hv vs  $(\alpha hv)^2$  graph from UV/Vis data for direct band gap analysis

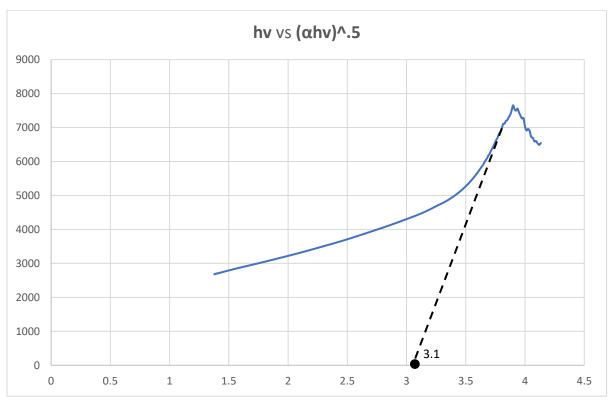


Fig. 5.3: hv vs ( $\alpha$ hv)^0.5 graph from UV/Vis data for indirect band gap analysis